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	Applicant(s) David E. Aspnes et al.	
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U.S. PATENT DOCUMENTS

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FOREIGN PATENT DOCUMENTS

	Ref	Document Number	Date	Country	Class	Subclass	Translation Yes	Translation No

OTHER DOCUMENTS

(Including Author, Title, Date, Pertinent Pages, Etc.)

	*BG	D.E. Aspnes, "Alignment of an Optically Active Biplate Compensator," *Applied Optics*, Vo. 10, pp. 2545-2546, November 1971.
	*BH	D.E. Aspnes et al., "High Precision Scanning Ellipsometer," *Applied Optics*, Vol. 14, pp. 220-228, January 1975.
	*BI	D.E. Aspnes et al., "Photomultiplier Linearization and System Stablization for Photometric Ellipsometers and Polarimeters," *SPIE*, Vol. 112-Optical Polarimetry, pp. 62-66, 1977.
	*BJ	D.K. Burge et al., "Effect of a Thin Surface Film on the Ellipsometric Determination of Optical Constants," *Journal of the Optical Society of America*, Vol. 54, No. 12, pp. 1428-1433, December 1964.
	*BK	B.D. Cahan, "Implications of Three Parameter Solutions to the Three-Layer Model," *Surface Science*, Vol. 56, pp. 354-372, 1976.
	*BL	D. Clarke et al., "*Polarized Light and Optical Measurment*," Chapter 4 and bibliography, Pergamon Press Ltd., Oxford, pp. 118-154 and 179-182, 1971.
	*BM	D. Clarke et al., "A Three-Channel Astronomical Photoelectric Spectropolarimeter," *Journal of Scientific Instruments (Journal of Physics E)*, Series 2, Vol. 1, pp. 409-412, 1968.
	*BN	W. Duncan et al., "Insitu Spectral Ellipsometry for Real-Time Measurement and Control," *Applied Surface Science*, Vol. 63, pp. 9-16, 1993.
	*BO	T. Gehrels (ed.), "Planets, Stars and Nebulae Studied with Photopolarimetry," University of Arizona Press, pp. 135-175, 1974.
	*BP	A. Hamnett et al., "A Ellipsometric Study of Polypyrrole Films on Platinum," *J. Electroanal Chem.*, Vol. 270, pp. 479-488, 1989.
	*BQ	P.S. Hauge, "Generalized Rotating-Compensator Ellipsometry," *Surface Science*, Vol. 56, pp. 148-160, 1976.
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	*BS	P.S. Hague, "A Rotating-Compensator Fourier Ellipsometer," *Engineering Technology*, 5 pages in length, March 1975.
	*BT	E.B. Hodgdon, "Theory, Design, and Calibration of a UV Spectrophotopolarimeter," *Applied Optics*, Vol. 4, No. 11, pp. 1479-1483, November 1965.
	*BU	Y.T. Kim et al., "Fast Scanning Spectroelectrochemical Ellipsometry: In-Situ Characterization of Gold Oxide," *Surface Science*, Vo. 233, pp. 341-350, 1990.
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	*BW	W. Paik et al., "Exact Ellipsometric Measurement of Thickness and Optical Properties of a Thin Light-Absorbing Film Without Auxiliary Measurements," *Surface Science*, Vol. 28, pp. 61-68, 1971.
	*BX	Z. Sekera, "Recent Developments in the Study of the Polarization of Sky Light," *Advances in Geophysics*, Vol. 3, pp. 43-104, 1956.
	*BY	D.E. Aspnes et al., "Rotating-Compensator/Analyzer Fixed-Analyzer Ellipsometer: Analysis and Comparison to Other Automatic Ellipsometers," *J. Opt. Soc. Am.*, Vol. 66, No. 9, Sept. 1976, pp. 949-954.
	*BZ	J.H.W.G. Den Boer et al., "Spectroscopic Rotating Compensator Ellipsometry in the Infrared: Retarder Design and Measurement," *Meas. Sci. Technol.*, Vol. 8, January 20, 1997, pp. 484-492.

Examiner	Date Considered 8/17/04

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